

ABSTRACT

A fluid mount (10) for an exposure apparatus (32) includes a first subsystem (12) and a second subsystem (14). The first subsystem (12) includes a first cylinder (18) and a first piston (20). The first piston (20) moves within the first cylinder (18) along a first axis (26). The second subsystem (14) includes a second cylinder (22) and a second piston (24). The second piston (24) moves within the second cylinder (22) along a second axis (28). Importantly, (i) the second subsystem (14) is stacked on top of the first subsystem (12), (ii) the second axis (28) is substantially coaxial with the first axis (26), and (iii) the first piston (20) is connected to the second piston (24) with a piston connector (16). The resulting fluid mount (10) has a relatively high load carrying capacity and a relatively small footprint.

Q
Q
D
D
C
C
B
B
A
A
P
P
H
H
T
T
20

15

20

25

30